



Docket No.: 0756-7289

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of: )  
Shunpei YAMAZAKI )  
Application No.: 10/820,781 ) Examiner: Unknown  
Filed: April 9, 2004 ) Group Art Unit:  
For: BEAM IRRADIATION APPARATUS, ) Not Yet Assigned  
BEAM IRRADIATION METHOD, )  
AND METHOD FOR MANUFACTURING )  
SEMICONDUCTOR DEVICE )

VERIFICATION OF TRANSLATION

Commissioner for Patents  
P.O.Box 1450  
Alexandria, VA 22313-1450

Sir:

I, Hikaru Tsuji, C/O Semiconductor Energy Laboratory Co., Ltd. 398, Hase, Atsugi-shi, Kanagawa-ken 243-0036 Japan, herewith declare:

that I am well acquainted with both the Japanese and English Languages; and

that to the best of my knowledge and belief the followings is a true and correct translation of the US Patent Application No. 10/820,781 filed on April 9, 2004.

I further declare that all statements made herein of my own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code, and that such willful false statements may jeopardize the validity of the application or any patent issuing thereon.

Date: this 13<sup>th</sup> day of August 2004

Name: Hikaru Tsuji